

OK TO ENTER: /JLP/

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:)	
)	Group Art Unit: 1762
Carl Woods)	
)	Examiner: Joseph Perrin
Application No: 10/817,620)	
)	Atty. Docket No: LAM2P474
)	
Filed: April 1, 2004)	
)	Date: Nov. 14, 2008
For: SUBSTRATE MENISCUS)	
INTERFACE AND METHODS FOR)	
OPERATION)	
_____)	

AMENDMENT

Honorable Commissioner for Patents
Alexandria VA 22313-1450

Dear Sir:

In response to the Advisory of Sept. 17, 2008 and an Examiner Conference of Nov. 13, 2008, this amendment is being submitted. A Notice of Appeal was filed in this case, and upon consideration of this amendment, the Examiner indicated that prosecution would be re-opened. Please enter this amendment and remarks.

The claims are reflected in the listing of claims which begin on page 6 of this paper.

Remarks begin on page 7 of this paper.

IN THE CLAIMS

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Currently amended) An apparatus for processing a substrate with a fluid meniscus to be applied to a surface of the substrate, comprising:

a docking surface configured to be oriented adjacent to and beside an edge of the substrate, the docking surface being coplanar with the substrate, and providing a transition interface to allow the fluid meniscus to enter and exit the surface of the substrate, the transition interface being spaced apart from the substrate; ~~and~~

a coupon magazine for holding the docking surface at one side and having a second side extend out to define the transition interface; and

at least one proximity head that forms the fluid meniscus.

2. (Original) An apparatus for processing a substrate as recited in claim 1, wherein the docking surface defines a docking station for the fluid meniscus.

3. (Canceled)

4. (Previously presented) An apparatus for processing a substrate as recited in claim 1, wherein the docking surface has a radial contour at the second side that defines the transition interface, and the radial contour of the docking surface is configured to match a radial contour of the substrate at a segment of the substrate that is less than a circumference of the substrate.

5. (Currently amended) An apparatus for processing a substrate with a fluid meniscus to be applied to a surface of the substrate, comprising:

a docking surface configured to be placed adjacent to and beside an edge of the substrate, the docking surface being coplanar with the substrate, and providing a transition interface to allow the fluid meniscus to enter and exit the surface of the substrate, the transition interface being spaced apart from the substrate; and

a coupon magazine for holding the docking surface at one side and having a second side extend out to define the transition interface, and the coupon magazine includes a top portion and a bottom portion for holding the docking surface;

at least one proximity head that forms the fluid meniscus;

wherein the docking surface has a radial contour at the second side that defines the transition interface, and the radial contour of the docking surface is configured to match a radial contour of the substrate at a segment of the substrate that is less than a circumference of the substrate.

6. - 8. (Canceled).

9. (Original) An apparatus for use in processing a substrate as recited in claim 5, wherein the docking station is a quartz material.

10. (Original) An apparatus for use in processing a substrate as recited in claim 5, wherein the docking station is a hydrophilic material.

11. (Previously presented) An apparatus for use in processing a substrate as recited in claim 5, further comprising,

a coupon magazine mount configured to hold the coupon magazine; and

rollers for positioning the substrate so that the substrate is spaced apart from the docking surface and coplanar.

12. (Original) An apparatus for use in processing a substrate as recited in claim 5, further comprising,

a leveling mechanism configured to move the docking station to be substantially coplanar with the substrate.

13. (Original) An apparatus for use in processing a substrate as recited in claim 12, wherein the leveling mechanism is configured to move the docking station in a vertical plane.

14. (Original) An apparatus for use in processing a substrate as recited in claim 12, wherein the leveling mechanism includes a screw configured to move a ball detent vertically.

15. (Original) An apparatus for use in processing a substrate as recited in claim 5, wherein the coupon magazine includes a sight window.

16.-20. (Canceled)

21. (Currently amended) An apparatus for processing a substrate with a fluid meniscus, comprising:

a coupon assembly for holding a docking station, the docking station having a curved docking surface for defining a transition interface to a radial segment of the substrate; ~~and~~

a coupon magazine mount for holding the coupon assembly, the coupon magazine mount defined to hold the curved docking surface of the docking station in an adjacent and coplanar orientation to a surface of the substrate; and

at least one proximity head that forms the fluid meniscus.

22. (Previously presented) The apparatus as recited in claim 21, further comprising:

a leveling mechanism being part of the coupon magazine mount, the leveling mechanism providing adjustment of the docking station so as to place curved docking surface in the coplanar orientation.

23. (Previously presented) The apparatus as recited in claim 21, wherein the docking station has an exterior portion and an interior portion that defines an opening, the exterior portion having sides for connecting to the coupon assembly and a side that includes the curved docking surface.

24. (Previously presented) The apparatus as recited in claim 21, wherein the docking station has a thickness that approximately matches a thickness of the substrate.

25. (Previously presented) The apparatus as recited in claim 23, wherein the coupon assembly includes a top portion and a bottom portion, and the top and bottom portion configured to hold the sides for connecting to the coupon assembly.

26. (Previously presented) The apparatus as recited in claim 21, wherein the adjacent orientation defines a separation between the substrate and the curved docking surface.

27. (Previously presented) The apparatus as recited in claim 26, wherein the separation is between about 0.001 mm and about 0.1 mm.

28. (Previously presented) The apparatus as recited in claim 21, further comprising:

rollers for positioning the substrate so that the substrate is spaced apart from the docking surface and in the coplanar orientation.

REMARKS

This paper is supplemental to the response to the Office Action of March 18, 2008, and the Advisory Action of September 17, 2008.

An Examiner conference was had on Nov. 13, 2008, concerning the status of the claims and the searched art. The Examiner indicated that a supplemental search would be conducted. A discussion was had regarding the currently claimed apparatus, and agreement was reached that the Applicant would recite the proximity head, as the proximity head is the structure that forms the claimed meniscus.

Based on this amendment, the Examiner indicated that the search scope would be better focused, and reconsideration would be granted. The Examiner further indicated that the current state of the Notice of Appeal would be withdrawn, and the Office would reopen prosecution, obviating the need to file a formal Appeal Brief. An extension is hereby paid electrically, to place the response current, allowing the Examiner to opine on the newly amended claims.

For at least these reasons, and those identified in the last Office Action response, the Applicants submit that the claims are patentable over the art of record. A Notice of Allowance is respectfully requested.

If the Examiner has any questions concerning the present amendment, the Examiner is kindly requested to contact the undersigned at (408) 749-6903. Please charge a one month extension to the deposit account. If any other fees are due in connection with filing this amendment, the Commissioner is also authorized to charge Deposit Account No. 50-0805 (Order No LAM2P474). A duplicate copy of the transmittal is enclosed for this purpose.

Respectfully submitted,
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